

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Hiroshi MASHIMA, et al.

SERIAL NO: 10/518,371

GAU: 1792

FILED: December 28, 2004

EXAMINER: GAMBETTA, KELLY M.

FOR: METHOD FOR PLASMA-ENHANCED CHEMICAL VAPOR DEPOSITION
AND APPARATUS FOR PLASMA-ENHANCED CHEMICAL VAPOR
DEPOSITION

**REQUEST FOR EXTENSION OF TIME
UNDER 37 C.F.R. 1.136**

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

SIR:

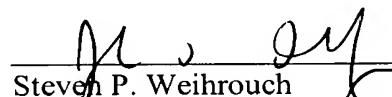
It is hereby requested that a **two** month extension of time be granted to July 11, 2009 for

- filing a response to the Official Action dated:
- responding to the requirements in the Notice of Allowability dated:
- filing the Formal Drawings. The Issue Fee due has been timely filed.
- responding to the Notice to File Missing Parts of Application dated:
- filing a Notice of Appeal. A timely response to the final rejection, due has been filed.
- Filing a RCE herewith. A Response to the Official Action was filed on: May 11, 2009
- Applicant claims small entity status. See 37 CFR 1.27.

The required fee of \$490.00 is being made by credit card payment online (if electronically filed), or is attached hereto (if paper filed), and any further charges may be made against the Attorney of Record's Deposit Account No. 15-0030.

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, P.C.



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